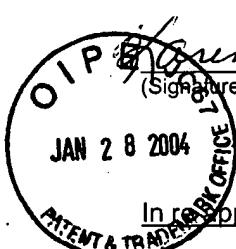


I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to : Commissioner of Patents and Trademarks, P. O. Box 1450, Alexandria, VA 22313-1450, on January 26, 2004. The applicant and/or attorney requests the date of deposit as the filing date. Depositor: Karen Cing-Mars



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : January 26, 2004

Rainer K. Krause, et al.: Group Art Unit: Not yet assigned

Serial No.10/707,288: Examiner: Not yet assigned

Filed: 12/03/03 : International Business Machines Corporation
2070 Route 52
Hopewell Junction, NY 12533

TITLE: A METHOD OF STRUCTURING OF A SUBSTRATE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

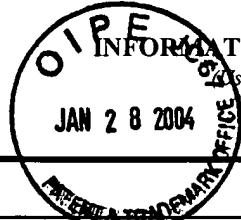
Pursuant to the duty of disclosure set forth in 37 C.F.R. 1.56, and further pursuant to the provisions of 37 C.F.R. 1.97 and 1.98, applicants hereby respectfully submit copies of the non-US patents and publications as listed on Form PTO-1449, attached hereto.

In citing these documents, no representation is made nor intended as to the pertinency or non-pertinency of the art, that better art than that listed is not available, or that other art is not applicable.

No fee is believed to be due for this submission. If any fees are required, however, the Commissioner is hereby authorized to charge such fees to Deposit Account No. 09-0458.

Respectfully submitted,
Rainer K. Krause, et al.

By 
Ira D. Blecker/ Attorney
Registration No. 29,894
Telephone No. 845-894-2580



INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

JAN 28 2004

Docket Number (Optional)

Application Number

Applicant(s)

Filing Date	12/03/03	Group Art Unit
-------------	----------	----------------

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

SPIE Micromachining & Microfabrication Symposium '96, "Imaging and Resist Technologies for the Micromachining Industry", David Craven, PP. 1-20

EXAMINER	DATE CONSIDERED
-----------------	------------------------

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.